

Form PTO-1479

**INFORMATION DISCLOSURE CITATION
IN AN APPLICATION**

(Use several sheets if necessary)

Docket Number (Optional)
AMY-002.01 (21424-201)

Application Number
10/079,985

Applicant
Hiro Tamura, et al.

Filing Date
February 21, 2002

Group Art Unit

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
UJH	AA US 6,327,855 B1	12/11/01	Hill et al.	60	528	
UJH	AB US 6,324,748 B1	12/04/01	Dhuler et al.	29	622	
UJH	AC US 6,308,631 B1	10/30/01	Smith et al.	102	254	
UJH	AD US 6,300,619 B1	10/09/01	Aksyuk et al.	250	216	
UJH	AE US 6,285,504 B1	09/04/01	Diemeer	359	578	
UJH	AF US 6,265,239 B1	07/24/01	Aksyuk et al.	438	52	
UJH	AG US 6,262,463 B1	07/17/01	Miu et al.	257	414	
UJH	AH US 6,255,757 B1	07/03/01	Dhuler et al.	310	307	
UJH	AI US 6,246,826 B1	06/12/01	O'Keefe et al.	385	140	
UJH	AJ US 6,222,954 B1	04/24/01	Riza	385	18	
UJH	AK US 6,171,886 B1	01/09/01	Ghosh et al.	438	73	
UJH	AL US 6,173,105 B1	01/09/01	Aksyuk et al.	385	140	
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UJH	AN US 6,166,478	12/26/00	Yi et al.	310	328	
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UJH	AP US 5,994,816	11/30/99	Dhuler et al.	310	307	
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UJH	AV US 6,087,743	07/11/00	Guckel et al.	310	40	
UJH	AW US 5,929,542	07/27/99	Ohnstein et al.	310	40	
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INFORMATION DISCLOSURE SECTION
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Group Art Unit

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OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages Etc.)

MH	BB	Bhansali et al.; "Prototype Feedback-Controlled Bidirectional Actuation System for MEMS Applications", Journal of Microelectromechanical Systems, 9 (2): 245-251 (June 2000)
MH	BC	Stephen Cohen, "Novel VOAs Provide More Speed and Utility", Laser Focus World, pp. 139-146 (November 2000)
MH	BD	Christenson and Guckel; "An Electromagnetic Micro Dynamometer", 1995 IEEE MEMS Proceedings, Amsterdam, the Netherlands, pp. 386-391, 29 Jan-2 February, 1995.
MH	BE	Gong and Zhou, "Micromachined Electromagnetic Actuator", Proceedings of the International Symposium on Test & Measurement, ISTM, PP. 23-26 (1999)
MH	BF	Guckel et al, "Laterally Driven Electromagnetic Actuators", Solid-State Sensor and Actuator Workshop, Hilton Head, South Carolina, pp. 49-52 (June 13-16, 1994)
MH	BG	Guckel et al.; "Design and Testing of Planar Magnetic Micromotors Fabricated by Deep X-Ray Lithography and Electroplating", The 7 th International Conference on Solid-State Sensors and Actuators, Yokohama, Japan, pp.76-79, (June 7-10, 1993)
MH	BH	Guckel et al.; "Fabrication and Testing of the Planar Magnetic Micromotor", J. Micromech. Microeng. 1: 135-138, (1991)
MH	BI	Guckel et al.; "Electromagnetic, Spring Constrained Linear Actuator with Large Throw", Actuator'94, pp. 52-55, (Bremen, Germany June 15-17, 1994)
MH	BJ	Guckel et al.; "Micromechanics for Actuators Via Deep X-Ray Lithography", SPIE Vol. 2194, pp. 2-10.
MH	BK	Guckel et al.; "Processing and Design Considerations for High Force Output- Large Throw Electrostatics, Linear Microactuators", Actuator 94, Bremen, Germany pp. 105-108, (15-17 June 1994) (Abstract)
MH	BL	H. Guckel and University of Wisconsin, Madison, "Photograph of Actuator," online, retrieved on February 1, 2002 from URL http://mems.engr.wisc.edu/images/linear/integrated_coil.jpg .
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MH	BO	Ohnstein et al.; "Tunable IR Filters with Integral Electromagnetic Actuators", Solid-State Sensor and Actuator Workshop, Hilton Head, South Carolina, pp. 196-199, (June 2-6, 1996)
MH	BP	Sadler et al.; "A Universal Electromagnetic Microactuator Using Magnetic Interconnection Concepts", Journal of Microelectromechanical Systems 9(4): 460-468, (December 2000)
MH	BQ	Sadler et al.; "A New Electromagnetic Actuator Using Through-Hole Plating of Nickel/ Iron Permalloy", Electrochemical Society Proceedings volume 98(20): 377-388

Form PTO-1449		Docket Number (Optional) AMY-002.01 (21424-201)		Application Number 10/079,985	
INFORMATION DISCLOSURE CITATION IN AN APPLICATION, <i>(Use several sheets if necessary)</i>		Applicant Hiro Tamura, et al.			
		Filing Date February 21, 2002		Group Art Unit	
		Wright et al.; "A Large -Force, Fully-Integrated MEMS Magnetic Actuator", Transducers 97, International Conference on Solid-State Sensors and Actuators, pp. 793-796, (Chicago, June 16-19, 1997)			
					
EXAMINER				DATE CONSIDERED 05/03	
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.					

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